

COPRA Plasma Technology

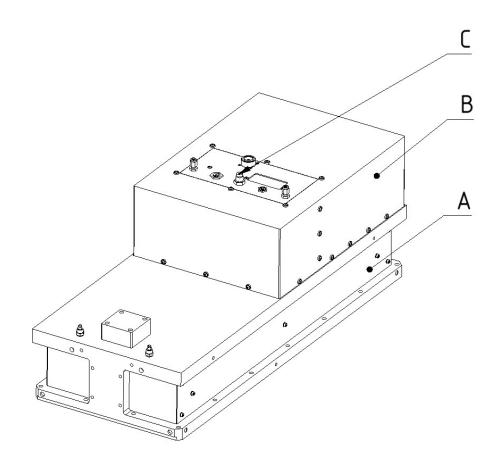
COPRA LS-Sources

Plasma Beam Sources for direct PECVD

COPRA LS-Sources

COPRA LS/Tech. Specs

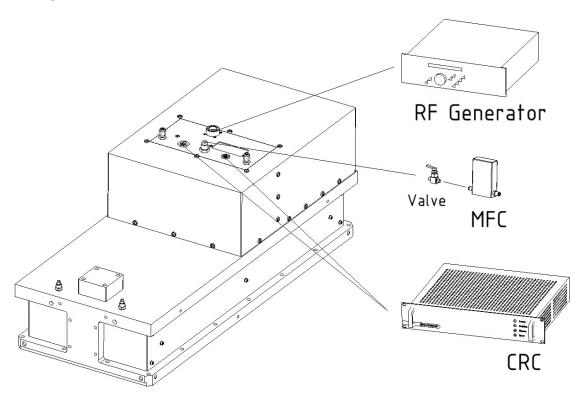
Technical Data	COPRA LS-Series
Excitation Frequency	13,56 MHz
Match	Remote Control via CRC
RF-Power	3.000 to 5.000 W
RF-Connection	7/16
CRC-Connection	Round pin plug, 15 pin
Water Connection	Serto 6 mm
Water Flow	> 21/min
Operation Gas Pressure	1 x 5 10 ^{-₄} to 5x 10 ⁻ ³ mbar
Gas Connection	VCR , Serto, Swagelok



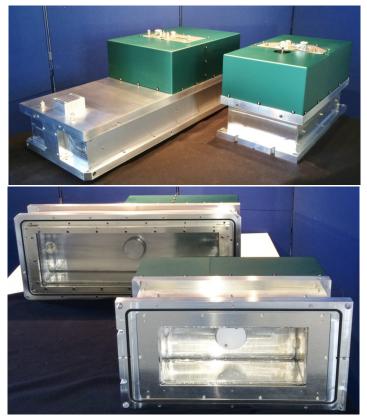
А	Al. Body - size can be customized
В	COPRA Standard Matchbox
С	Process Gas inlet (optional in Top-plate)

COPRA LS-Sources

Installation Drawing



Main Features



- Long Term Process stability
- Easy to handle
- Quasi Maintenance free
- Large Area PECVD
- Scalable to customers needs
- Low operating costs
- Integrated Matchbox
- Low contamination level
- High Amount of O+
- Current Control independent from Energy
- Simple to mount
- Selective activation of surface

COPRA LS-Sources

2015[©] Copyright by CCR GmbH Troisdorf. All rights are reserved. Without written permission, no part of this paper covered by copyright herein may be reproduced or copied in any form or by any means.

The COPRA technology is patent protected! US 6,936,144 B2

CCR TECHNOLOGY

Camp-Spich-Str. 3a D-53842 Troisdorf Tel.: +49 (0) 2241-93215-0 Fax.: +49 (0) 2241-93215-200 Email: contact@ccrtechnology.de www.ccrtechnology.de

